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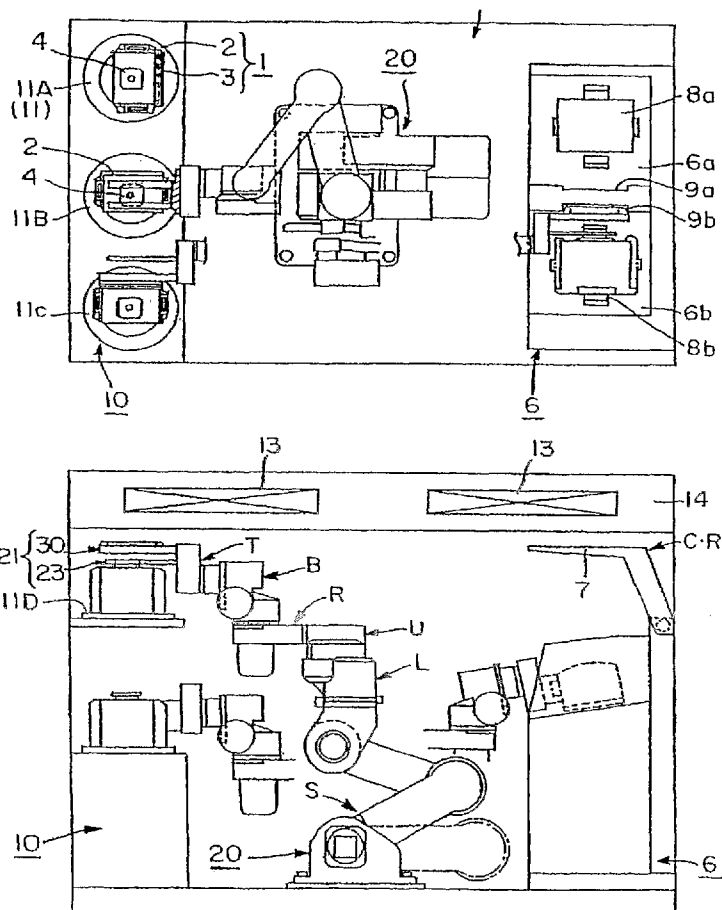
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(54) Title: **WAFER CARRIER CLEANING SYSTEM**



(57) Abstract: Disclosed is a system and method for automating the handling of wafer carriers for a washing procedure. The system according to one embodiment comprises disposing a robot between a loading and unloading section, and the washing apparatus. The robot includes a hand that may comprise a first engaging component for operably grasping the carrier body and a second engaging component for operably engaging the carrier door. In one embodiment, the robot removes the carrier door from the carrier body and grasps the body while maintaining possession of the door. The carrier door and carrier body are then placed in respective positions within the washing apparatus. This procedure is reversed for retrieval of the clean wafer container components.



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